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**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Akifumi KAMIJIMA et al.

Group Art Unit: 1756

Application No.: 09/966,080

Examiner: J. Ruggles

Filed: October 1, 2001

Docket No.: 110735

For: A METHOD FOR FABRICATING A RESIST PATTERN, A METHOD FOR  
PATTERNING A THIN FILM AND A METHOD FOR MANUFACTURING A  
MICRO DEVICE

**STATEMENT OF SUBSTANCE OF INTERVIEW**

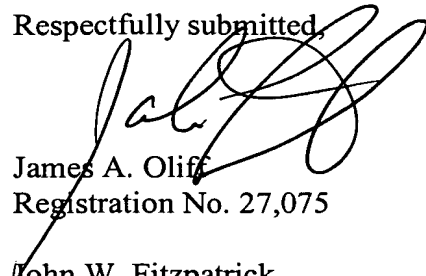
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

A personal interview was conducted by Applicants' representative and Examiner Ruggles and SPE Huff on August 2, 2004. During the personal interview, the claim amendments and arguments provided in the July 14, 2004 Amendment were reviewed. Additionally, Applicants' representative presented experimental results in support of the argument that the applied references do not disclose or suggest each and every feature recited in the rejected claims.

Examiner Ruggles indicated that the arguments and amendments would be given further consideration upon review of the July 14, 2004 Amendment.

Respectfully submitted,



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JAO:JWF/lbg

Date: August 3, 2004

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